

# RADICAL PLASMA SOURCE (REMOTE PLASMA SOURCE) - MA2000C-783BB

**Category:** Plasma components



UNDER  
PROGRESS

## ADDITIONAL INFORMATION

<b>Typ</b>	Radical plasma source (Remote Plasma Source)
<b>Process</b>	Etching & Deposition
<b>Output Connection Type</b>	
<b>Dielectric material</b>	Ceramics
<b>Mains voltage nominal [V]</b>	230 / 208
<b>Output Power CW [W]</b>	2000
<b>Frequency [MHz]</b>	2450